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Sheet 1 of 2

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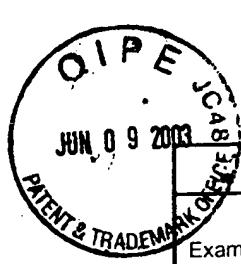
Application Number	10/072,656
Filing Date	February 7, 2002
First Named Inventor	Eric Prophet
Group Art Unit	2811
Examiner Name	Not Yet Assigned
Attorney Docket Number	269/132

U.S. PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code ² (if known)			
Loke		US-3,802,523	04/09/1974	Clark	
		US-5,079,657	01/07/1992	Aronoff et al.	
		US-5,307,593	05/03/1994	Lucker et al.	
		US-5,482,564	01/09/1996	Douglas et al.	
		US-5,506,017	04/09/1996	Ranjan et al.	
		US-5,512,374	04/30/1996	Wallace et al.	
		US-5,542,295	08/06/1996	Howe et al.	
		US-5,599,590	02/04/1997	Hayashi et al.	
		US-5,658,636	8/19/1997	Reed et al.	
		US-5,662,771	09/02/1997	Stouppe	
		US-5,700,379	12/23/1997	Biebl	
		US-5,727,445	03/17/1998	Sheldon	
		US-5,912,791	06/15/1999	Sundaram et al.	
		US-5,942,279	08/24/1999	Wudu	
		US-6,036,786	03/14/2000	Becker et al.	
		US-6,127,744	10/03/2000	Streeter et al.	
		US-6,127,765	10/03/2000	Fushinobu	
		US-6,187,413	02/13/2001	Kuo et al.	
↓	Loke				

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
Loke		ABE, Takeshi et al., Control of Liquid Bridging Induced Stiction of Micromechanical Structures, J.Micromech. Microeng. 6 (1996) 213-217	
Loke		ALMANZA-WORKMAN, A.M., et al., Water Dispersible Silanes for Wettability Modification of Polysilicon for Stiction Reduction in Silicon Based Micro-Electromechanical Structures	
Loke		ASHURST, W.R. et al., Alkene Based Monolayer Films as Anti-Stiction Coatings for Polysilicon MEMS, Berkley Sensor and Actuator Center	
Loke		ASHURST, W.R. et al., Dichlorodimethylsilane as an Anti-Stiction Coating for MEMS, National Science Foundation Report	
Loke		HARSH, K.F., Dealing With MEMS Stiction and Other Sticking Problems (website printout)	
Loke		KIM, B.H. et al., A New Organic Modifier for Anti-Stiction, Journal of Microelectromechanical Systems, Vol. 10, No. 1, March 2001, pp 33-40	
Loke		KIM, Chang-Jin et al., Comparative Evaluation of Drying Techniques for Surface-Micromachining, submitted to Sensors & Actuators	
Loke		MABOUDIAN, R. et al., Self-Assembled Monolayers as Anti-Stiction Coatings for MEMS: Characteristics and Recent Developments	
Loke		MABOUDIAN, R., Critical Review: Adhesion in Surface Micromechanical Structures, J. Vac. Sci. Technol. B 15(1), Jan/Feb 1997, pp 1-20	
Loke		MASTRANGELO, C.H., Suppression of Stiction in MEMS	



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Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
Loke		TAS, N. et al., Side-Wall Spacers for Stiction Reduction in Surface Micromachined Mechanisms	
Loke		TAS, Niels et al., Stiction in Surface Micromachining, 1996, Pages 385-397, IOP Publishing Ltd., United Kingdom	
Loke		YANG, Lung-Jieh et al., Photo-Patternable Gelatin as Protection Layers in Surface Micromachinings	
Loke		YAO, Tze-Jung et al., BrF3 Dry Release Technology for Large Freestanding Parylene MEMS,	

Examiner Signature	Loke	Date Considered	8/20/03
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

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